

Original and Supplementary Data for Paper:

“Bipolar device fabrication using a scanning tunneling microscope”

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# Fig.1 - Original and supplementary STM images

## STM Image processing:

- STM images were acquired with the Omicron Scala software using a unix control computer. Later (images in Figs. 4 and 5) we used a custom built in-house control software and hardware to acquire STM scans.
- The Gwyddion software package and pyplot was used to plot STM images
- Most Images were processed by subtracting a linear background
- In a few cases a line-by-line average subtraction was made
- For the figures in the paper the images were cropped, in some cases corrected for drift and scaled using the period of the dimer rows of the silicon (100) surface.

# Fig. 1

Fig. 1b

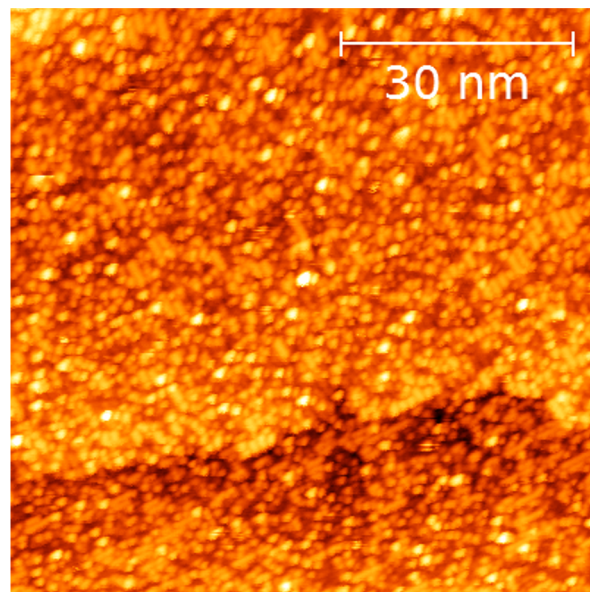


Fig. 1c

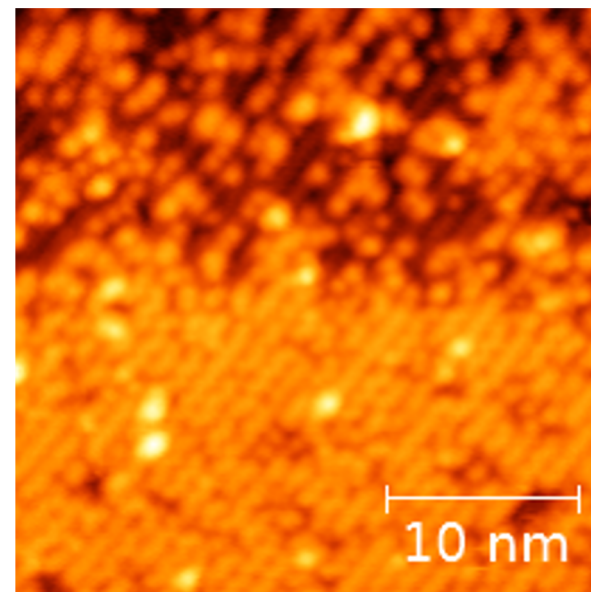


Fig. 1e

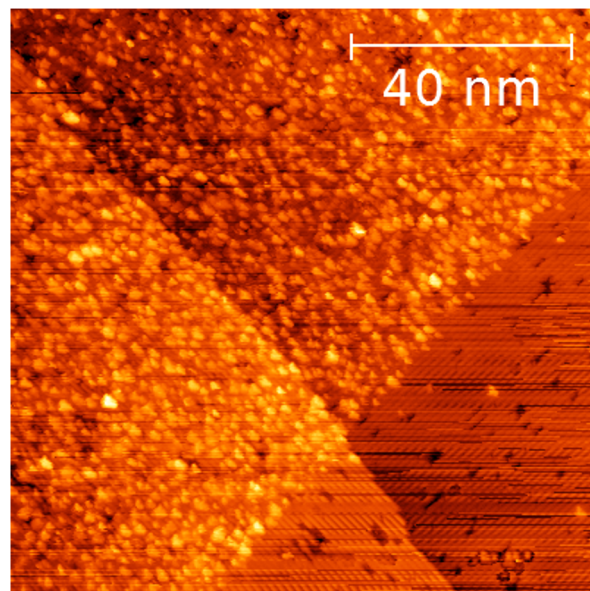


Fig. 1d

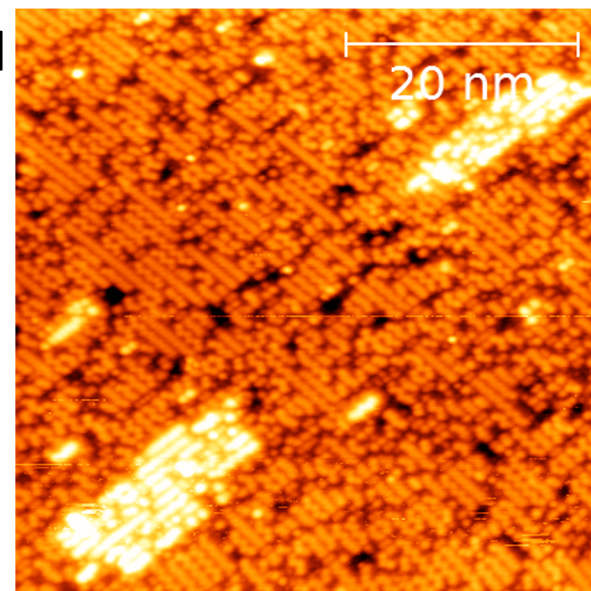
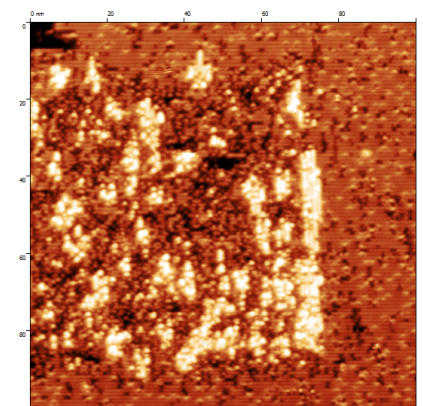
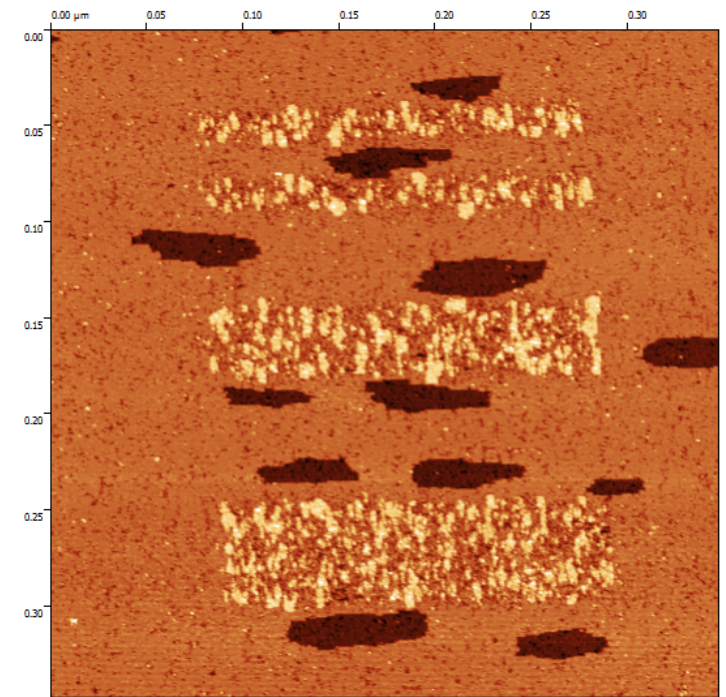
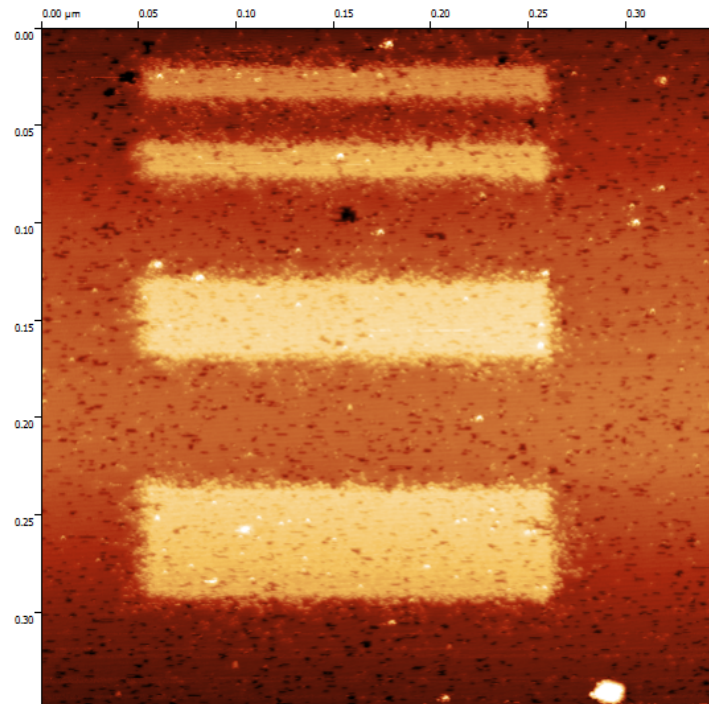


Fig. 1

Fig. 1f and g

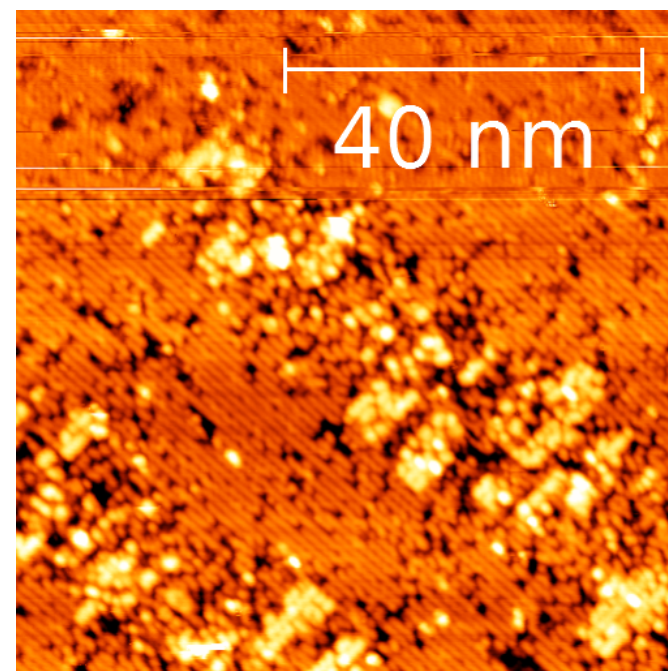
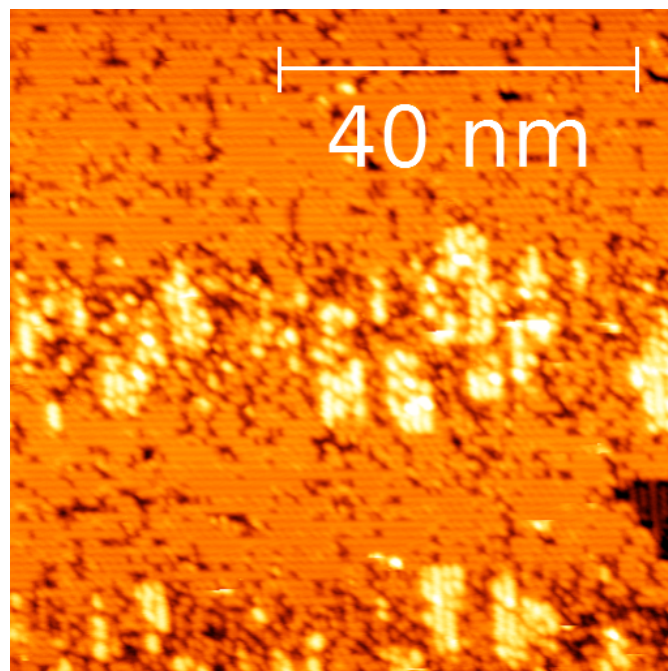
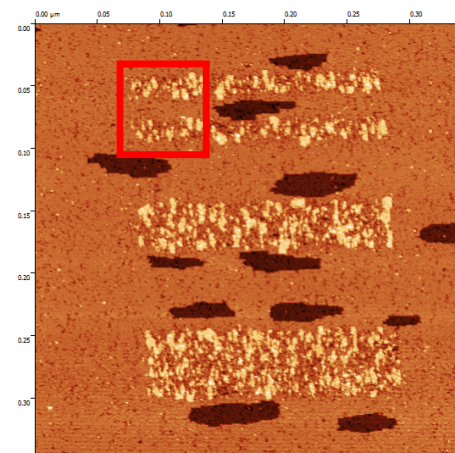




# Fig. 1

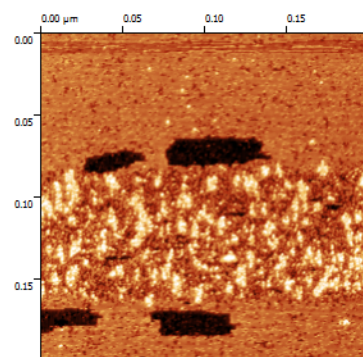
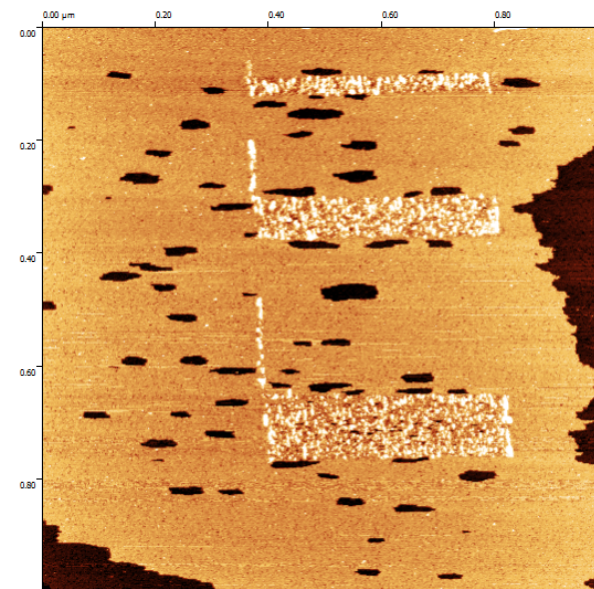
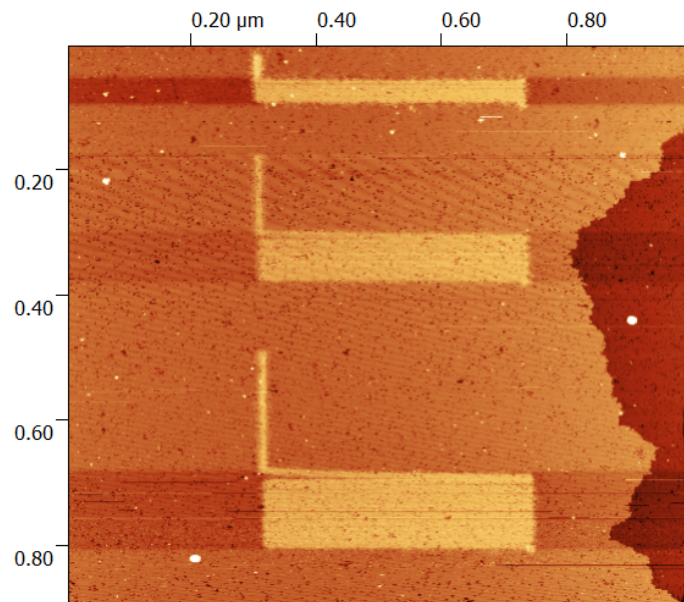
Fig. 1f and g

zoom of upper region for Fig. 1g



# Fig. 1

Fig. 1f and g – additional data (not shown in paper)

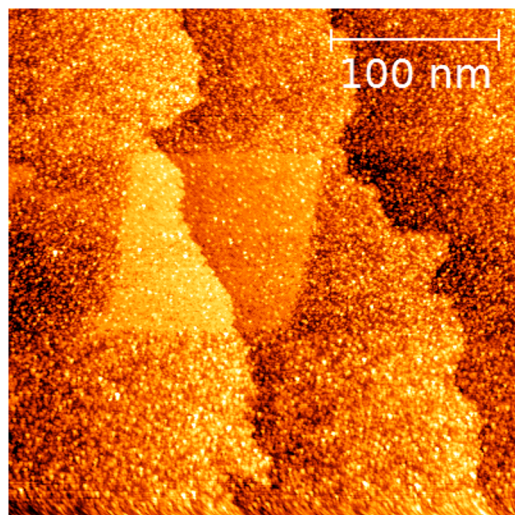




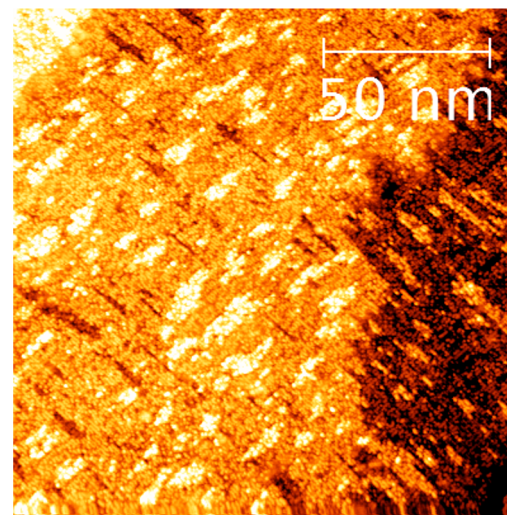
# Fig. 1

Additional data (not shown in paper):  
9L diborane dose and different in-situ anneals

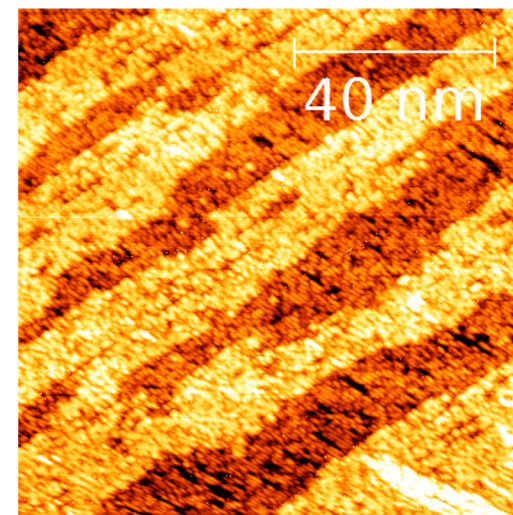
350C 5min



350C 5min + 450C 5min



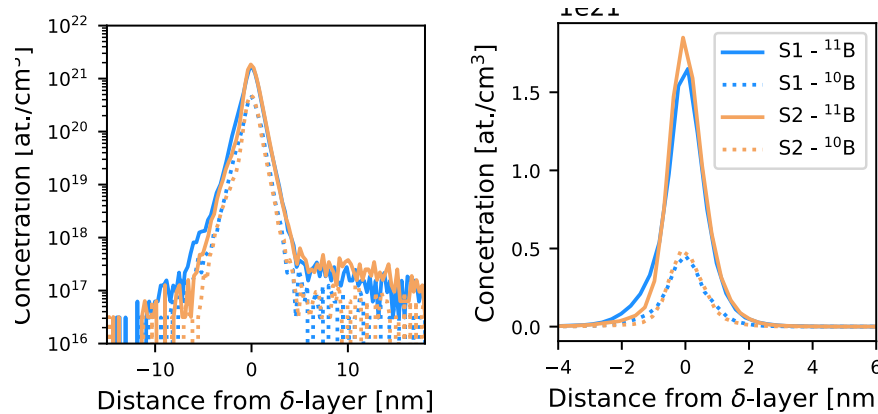
350C 5min + 450C 5min +  
600C 2.5min + 800 0.5min



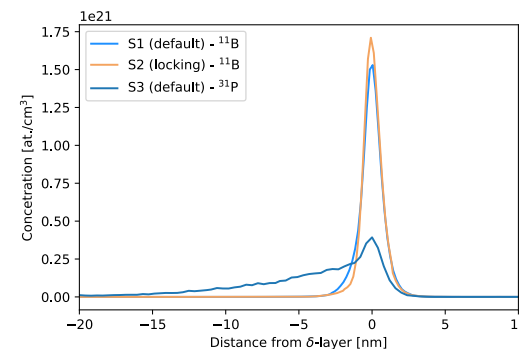
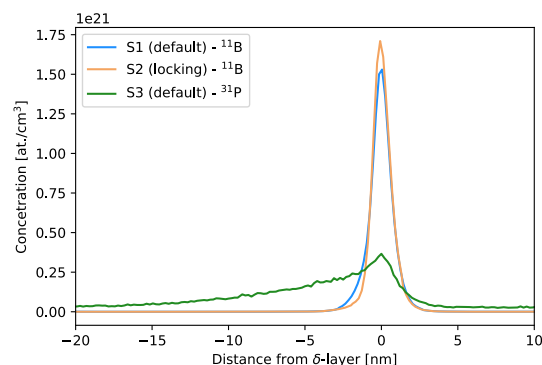
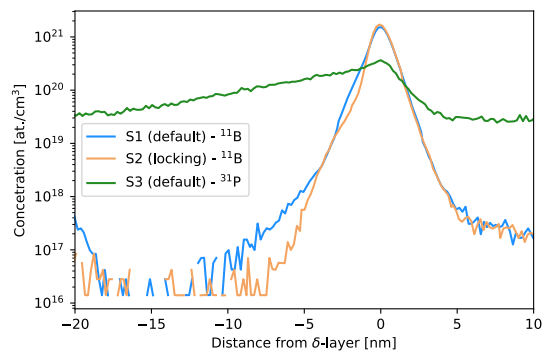
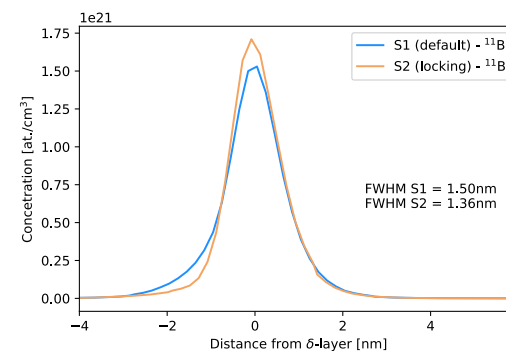
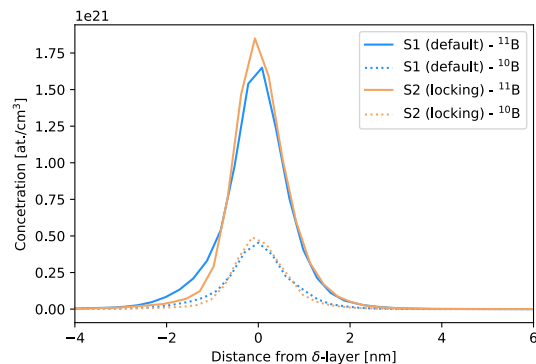
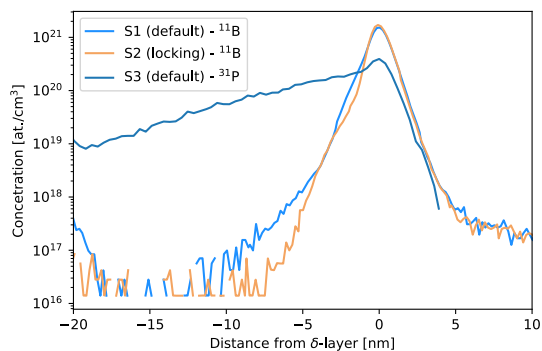
# Fig. 2

SIMS data for:

- phosphorus  $\delta$ -layer
- boron  $\delta$ -layer
- boron with locking  $\delta$ -layer



Comments & Info.csv  
 Data\_BinSi\_Ref.csv  
 Data\_PinSi\_Ref.csv  
 Data\_S1\_InROI.csv  
 Data\_S1\_NextToROI.csv  
 Data\_S2\_InROI.csv  
 Data\_S2\_NextToROI.csv  
 Data\_S3\_P-template\_InROI.csv  
 Data\_S3\_P-template\_NextToROI.csv  
 Depths.csv







# Fig. 3 - List of Samples

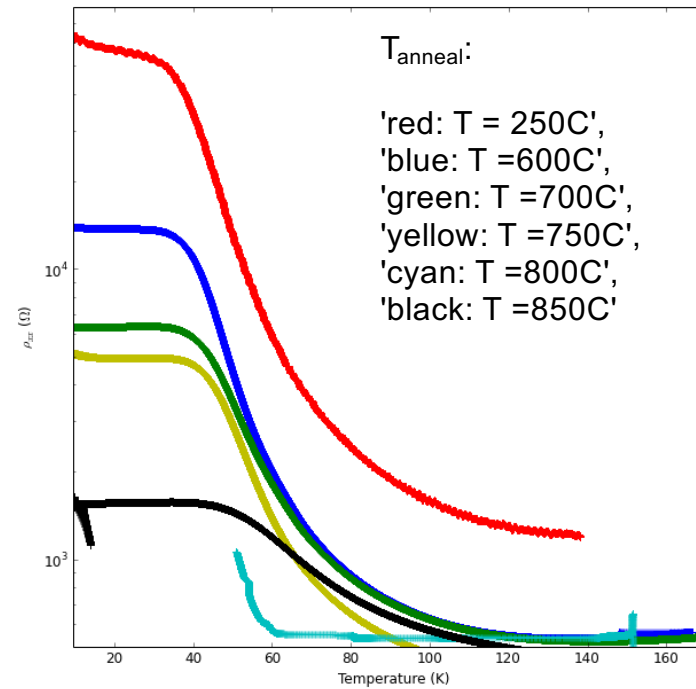
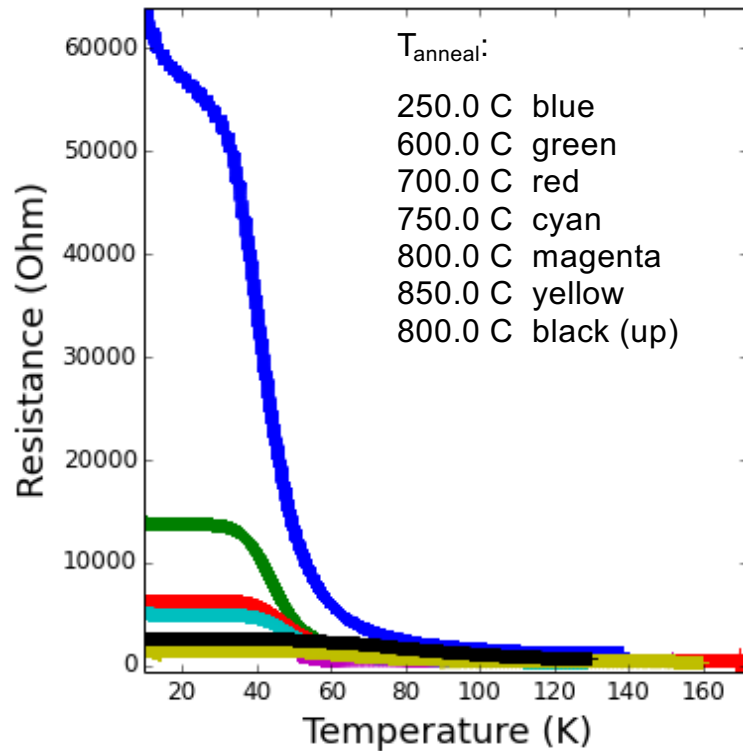
Sample name	Symbol	part	type	Dose	Anneal T+time	Anneal type	Hallbar	Cryostat	Comments	Si overgrowth
		Notes		STM manipulator with resistive and ZUP	contact anneal not mentioned for any annealing procedure, in-situ Pyrometer if not otherwise stated	In-situ anneal in general with 1.5-2nm Si cap				standard, starting sample with resistive and start direct keeping it below 300C in Pyrometer pyro below 300C
nSi#40		all	B delta	2.7L (slow open) 22%; 100-130C	350C Pyro 1min 250C 2min contact anneal	In-situ Ex-situ	yes, Pt		first try of B delta	
A	☆	middle, bonded						Oxford	no measure between	
B		1A			410C 2min	Ex-situ				
C		2A			650C 2min	Ex-situ				
D		1B			850C 2min	Ex-situ				
		2B								
nSi#48			B delta	338L heating forgot to note, probably 30%		Ex-situ	yes, Pt			
	△	1A			250C 2min / 800C 10s			Oxford	sample cut and annealed after hallbar	18nm, standard
		1B, bonded			250C 2min / 800C 1.5s			Oxford		
B		middle, bonded			250C 2min / 600C 2min / 800C 4s / 850C			Oxford		
A		2A/B, bonded			250C 2min / 800C 2min			Oxford		
nSi#54		all	B delta	570L		Ex-situ	yes, Pt		sample cut and annealed after hallbar	18nm, standard, temperature the lowest as possible with direct. for for Grenoble as a backup
A, C	□	1A, bonded			250C 2min / 700C 2min / 850C 2min			ppms		
B, D, F		middle			250C 2min / 700C 2min / 900C 2min			ppms		
E		2A / 2B			600C 2min / 750C 2min / 850C 80s 800C 2min			Ppms / Oxford Ppms / Oxford	new contacts after sample lost	
nSi#83		all	B delta	900L, 30%	13s 850C Pyro	In-situ	yes Pt			
A	×	middle, bonded						Oxford	temp possibly a bit lower, mainly watched current	15nm, start standard, after 2nm turn out sample, 850C 5sec (might have been even shorter difficult with power supply), continue growth 5min 350C, then
		1A								
		1B (dirt)								
		2A								
		2B								
nSi#88		all	B delta	570L, 30%	10s, 830C 2.5A, last 2-3s corrected to 850C	In-situ	yes, Pt		2nm interlayer standard, then incorporation anneal	15nm standard
A	+	middle, bonded 1A,1B, 2A,2B						Oxford		
nSi#129		all	B delta	90L,25% 95c-176C	1.5min 350C, 0.5min 405C	In situ	yes, Pt			
		all			contact anneal 250C 1.5min	Ex-situ			no interlayer before in-situ anneal. ex-situ in RTA clean room	18nm standard
		middle			1080C 2min					
		1A			850C 2min, 931C 2min	Ex-situ				
A	◇	1B			410C 2min, ?C 2min	Ex-situ				
B		2A			650C 2min	Ex-situ				
		2B			1000C 2min	Ex-situ			dirty	

in-situ 250C 2min

# Fig. 3a Temp-sweeps overview (PPMS)

*nSi#54 590L dose*

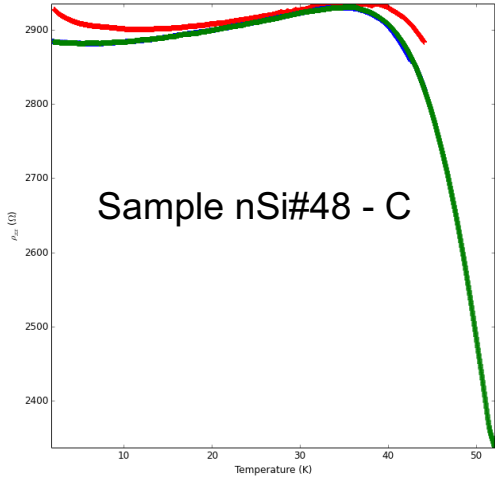
Sample nSi#54



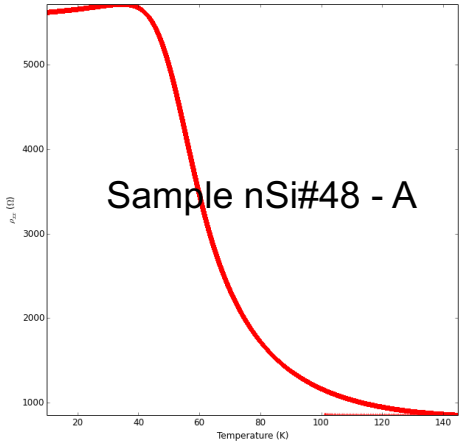
in-situ 250C 2min

# Fig. 3a Temp-sweeps overview (Oxford)

*nSi#48 338L dose*



T sweep  
Tanneal = 800C 4s



T sweep  
Tanneal=800C 10s  
less Diborane



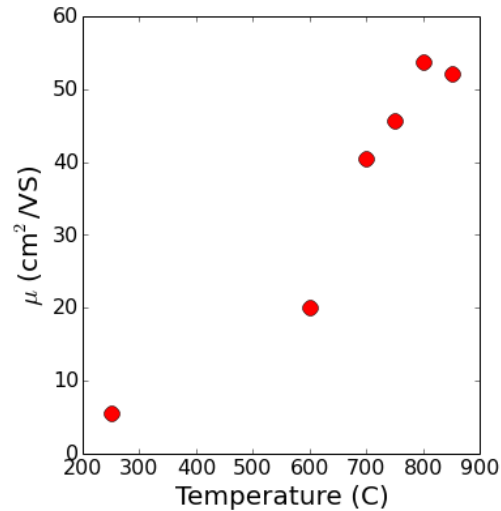
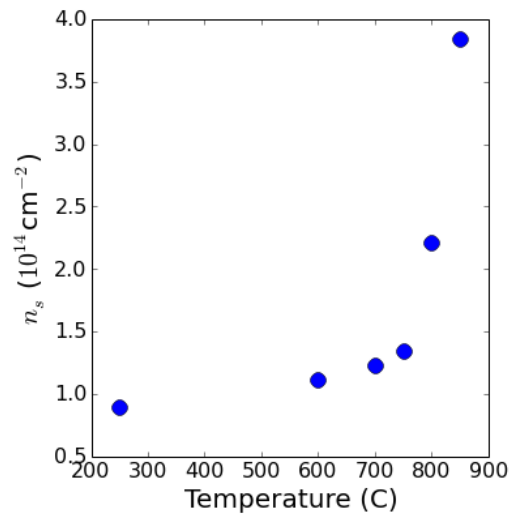
in-situ 250C 2min

# Fig. 3c-d Magneto-resistance Data nSi#54

*nSi#54 590L dose*

- Measured on PPMS system
- 900C sample had contact problems after anneal

Measurement Temperature  $T_M=10K$



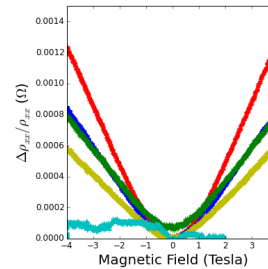
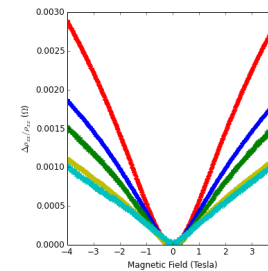
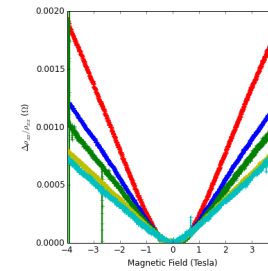
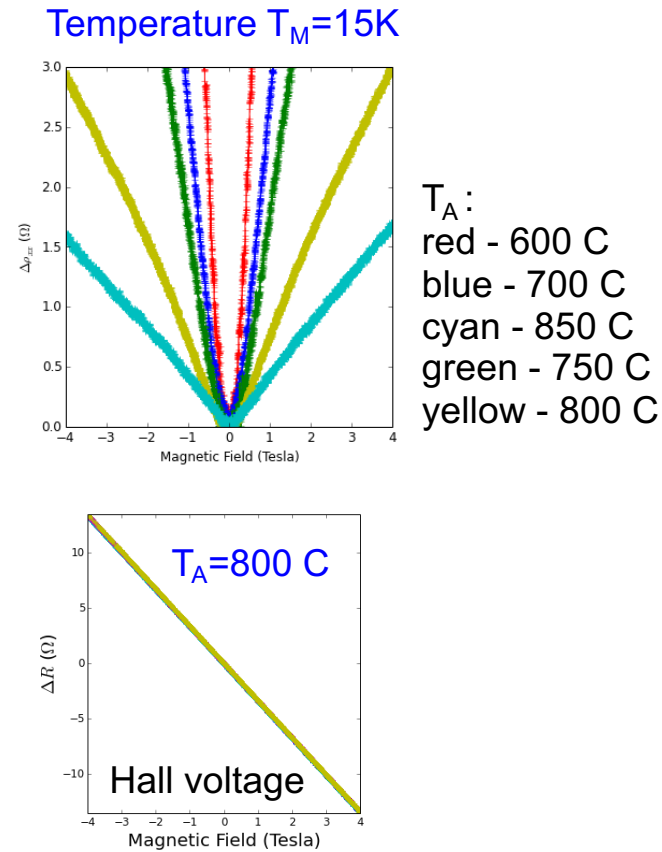
mobility and density as a function of annealing temperature extracted from the following Hall measurements

Sample nSi#54

in-situ 250C 2min

# Fig. 3c-d Magnetoconductance Data nSi#54

*nSi#54 590L dose*



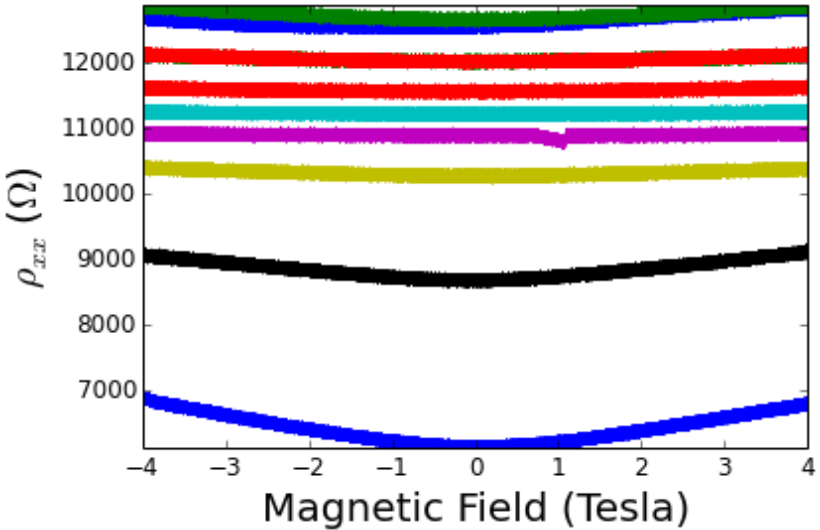
Sample nSi#54

in-situ 250C 2min

# Fig. 3c-d B sweeps 250C sample (PPMS)

Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	nan	0.9	5.54	12568.93	0.08
green	15	0.94	5.49	12039.13	0.083
red	20	0.98	5.51	11578.03	0.086
cyan	25	1	5.54	11231.01	0.089
magenta	30	1.04	5.51	10913.3	0.092
yellow	35	1.05	5.79	10282.22	0.097



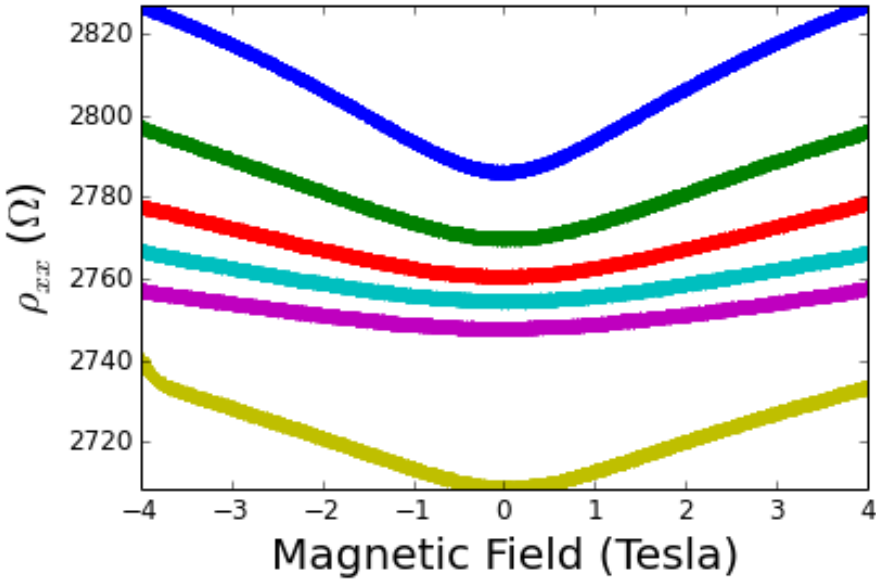
Sample nSi#54

in-situ 250C 2min

# Fig. 3c-d B sweeps 600 C sample (PPMS)

Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0 (mS)
blue	10	1.12	20.06	2786.1	0.359
green	15	1.14	19.72	2769.85	0.361
red	20	1.16	19.51	2760.54	0.362
cyan	25	1.17	19.35	2754.51	0.363
magenta	30	1.18	19.27	2747.69	0.364
yellow	35	1.18	19.46	2708.75	0.369



Sample nSi#54

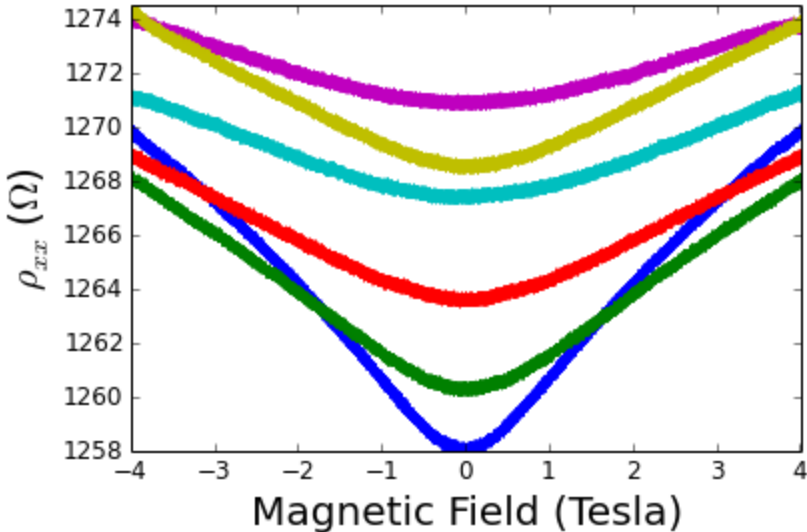


in-situ 250C 2min

# Fig. 3c-d B sweeps 700 C sample (PPMS)

Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	10	1.23	40.46	1258.1	0.795
green	15	1.24	39.96	1260.34	0.793
red	20	1.25	39.57	1263.65	0.791
cyan	25	1.26	39.21	1267.46	0.789
magenta	30	1.26	38.92	1270.95	0.787
yellow	35	1.27	38.89	1268.58	0.788

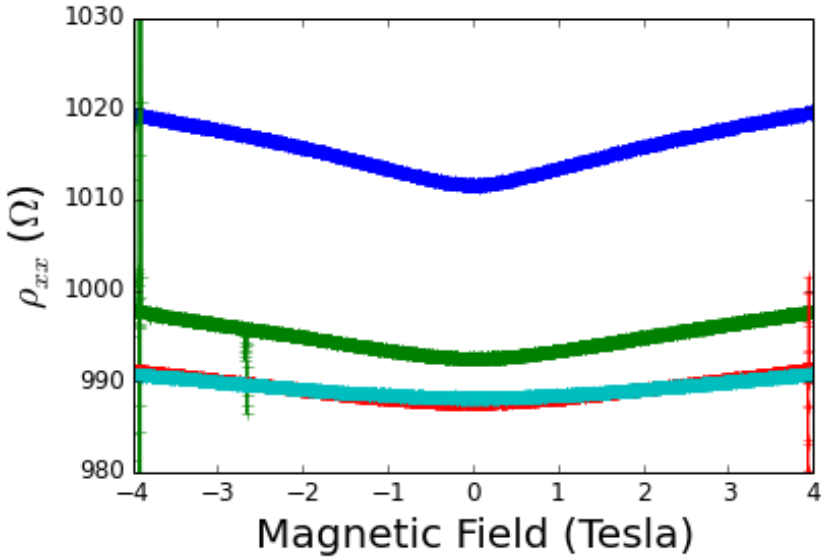


in-situ 250C 2min

# Fig. 3c-d B sweeps 750 C sample (PPMS)

Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	10	1.35	45.74	1011.62	0.989
green	15	1.39	45.37	992.54	1.008
red	20	1.41	44.71	987.64	1.013
cyan	25	1.42	44.53	988.16	1.012



Sample nSi#54

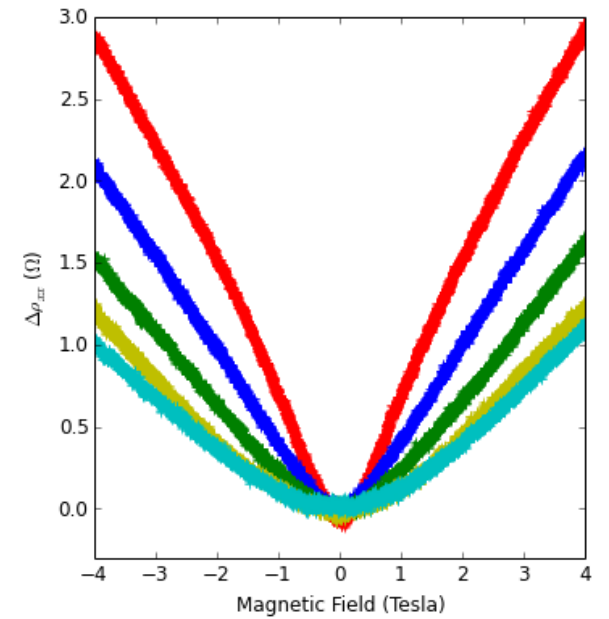
in-situ 250C 2min

# Fig. 3c-d B sweeps 800C sample (Oxford)

Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0 (mS)
blue	4	2.15	56.34	516.05	1.938
green	6	2.18	54.81	521.95	1.916
red	8.7	2.27	52.67	522.05	1.916
cyan	10.8	2.4	49.75	522.27	1.915
magenta	4	2.22	54.1	520.88	1.92
yellow	6	2.21	54.21	521.97	1.916

blue - 15.0  
cyan - 30.0  
green - 20.0  
yellow - 25.0  
red - 10.0



Sample nSi#54

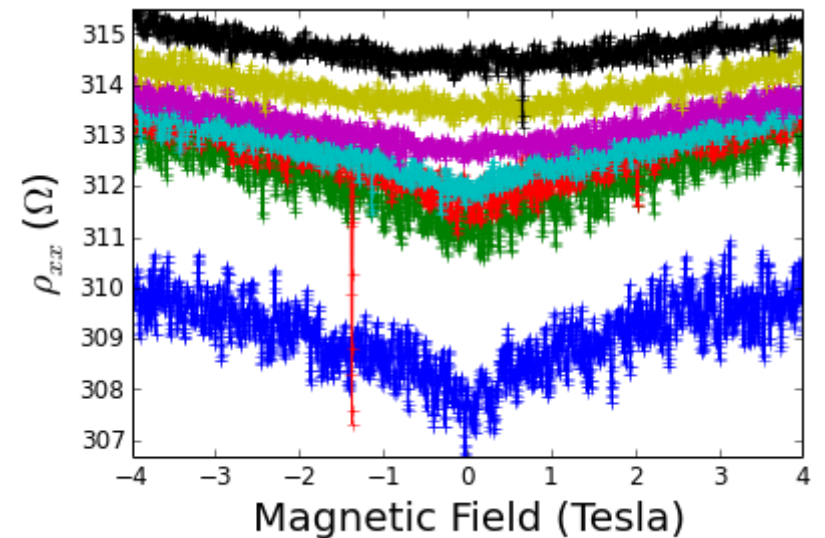
in-situ 250C 2min

# Fig. 3c-d B sweeps 850C sample (Oxford)

## Measurement Temperature dependence

T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
4.6	2.17	93.65	307.72	3.25
6.8	3.21	62.41	311.17	3.214
8.8	3.4	58.92	311.71	3.208
10.9	3.38	59.15	311.96	3.206
16.1	3.62	55.21	312.74	3.198
21.2	3.57	55.76	313.56	3.189
25.9	3.52	56.46	314.46	3.18
4.6	-2.35	86.24	307.87	3.248
6.7	3.43	58.51	311.16	3.214
8.8	3.2	62.51	311.77	3.207
10.9	3.57	56.04	312.02	3.205
15.7	3.26	61.29	312.65	3.198
20.3	3.25	61.23	313.45	3.19
24.7	3.4	58.49	314.28	3.182

4.6 K - blue  
6.8 K - green  
8.8 K - red  
10.9 K - cyan  
16.1 K - magenta  
21.2 K - yellow  
25.9 K - black



Sample nSi#54

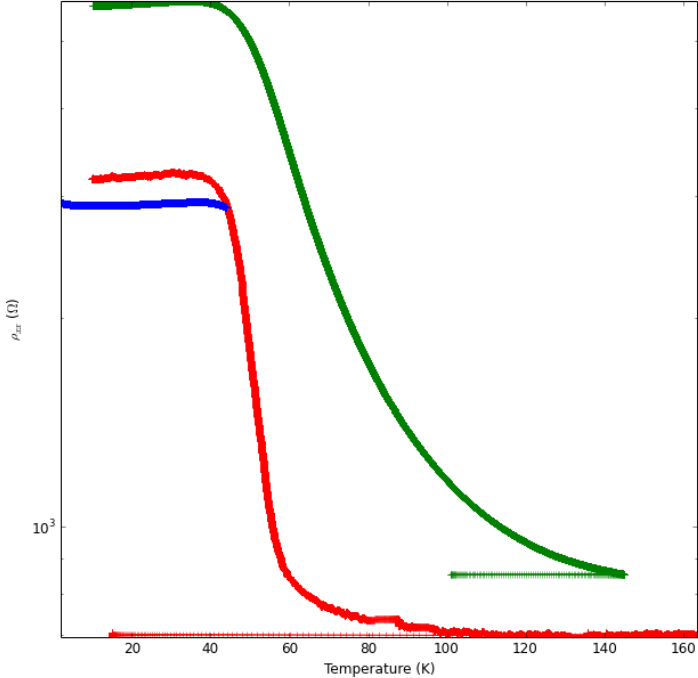


# Fig. 3c-d      Sample nSi#48

Annealing time dependence at 800C:

- At least for 10s still seems metallic down to 10K
- Densities for 4s better than for others! But close to 120s, 10s about 2x smaller
- For 4sec at low T resistance rising again? (others not measured for such small T)

$T_{\text{anneal}}$  :  
red = 2min  
blue = 4sec  
green = 10sec

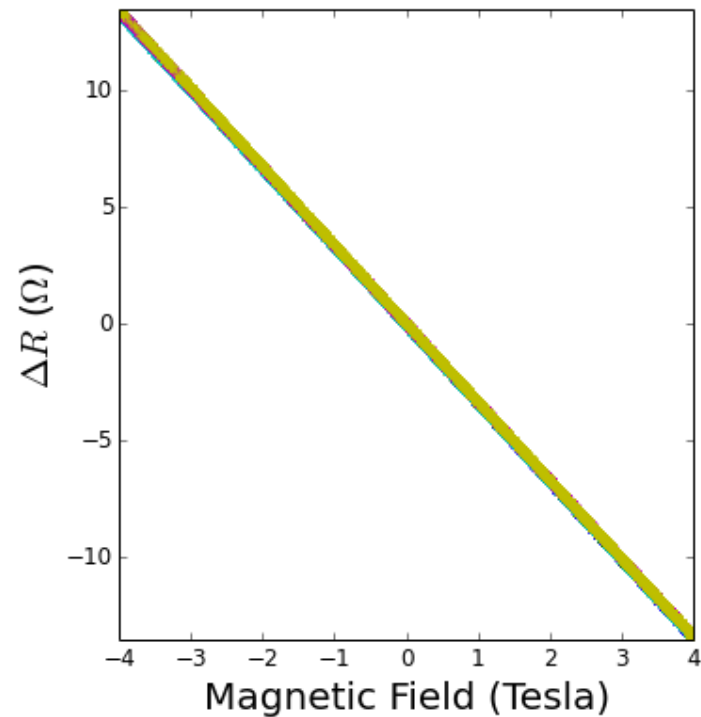
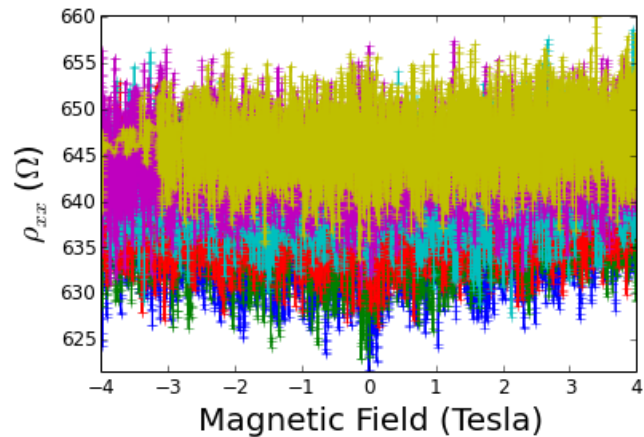


in-situ 250C 2min

# Fig. 3c-d B sweeps 800C 120s (PPMS)

Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0 (mS)
blue	10	-1.86	52.76	635.17	1.574
green	15	-1.87	52.51	635.86	1.573
red	20	-1.87	52.24	638.25	1.567
cyan	25	-1.87	51.99	641.45	1.559
magenta	30	-1.87	51.82	644.02	1.553
yellow	35	-1.87	51.81	645.93	1.548



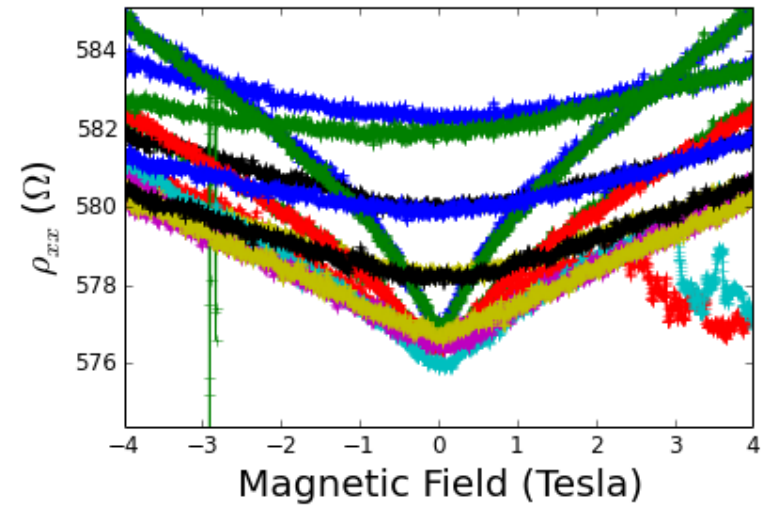
Sample nSi#48

in-situ 250C 2min

# Fig. 3c-d B sweeps 800C 4s (Oxford)

## Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0 (mS)
blue	2.6	2.07	52.25	576.96	1.733
green	4.6	2.09	51.89	576.48	1.735
red	6.6	2.1	51.65	576.49	1.735
cyan	8.7	2.1	51.5	576.46	1.735
magenta	10.8	2.11	51.34	576.88	1.733
yellow	16.1	2.11	51.04	578.28	1.729
black	21	2.12	50.83	580.02	1.724
blue	25.7	2.12	50.63	582.29	1.717
green	2.7	2.07	52.22	576.99	1.733
red	4.6	2.09	51.86	576.48	1.735
cyan	6.6	2.1	51.69	575.98	1.736
magenta	8.6	2.1	51.5	576.45	1.735
yellow	10.7	2.11	51.34	576.76	1.734
black	15.7	2.11	51.05	578.26	1.729
blue	20.2	2.12	50.85	579.89	1.724
green	24.6	2.12	50.63	582.31	1.717



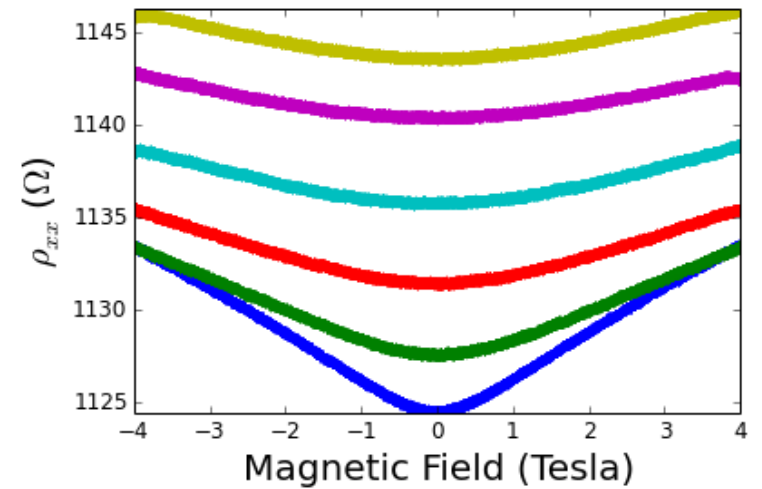
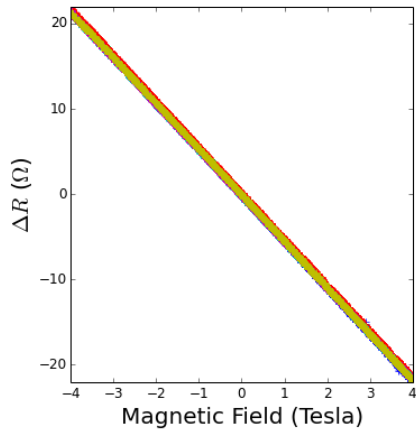
Sample nSi#48

in-situ 250C 2min

# Fig. 3c-d B sweeps 800C 10s (PPMS)

Temperature dependence

	T(K)	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	10	1.15	48.34	1124.53	0.889
green	15	1.16	47.91	1127.62	0.887
red	20	1.16	47.58	1131.47	0.884
cyan	25	1.16	47.27	1135.82	0.88
magenta	30	1.16	47.11	1140.43	0.877
yellow	35	1.16	47.15	1143.61	0.874

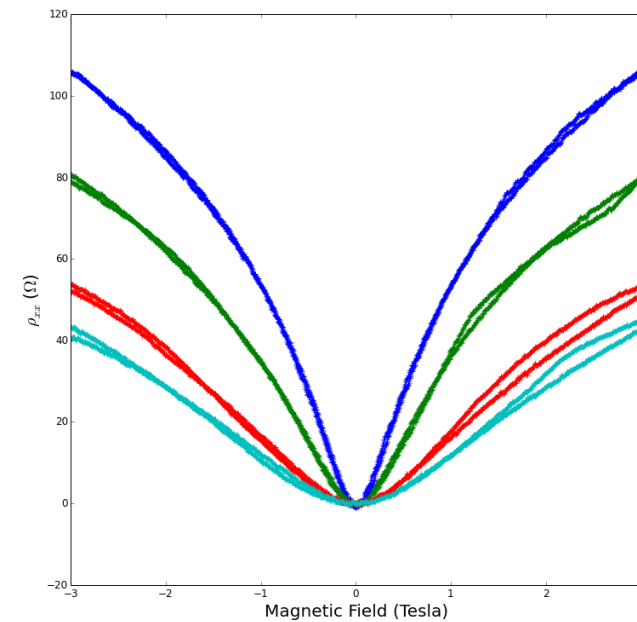


Sample nSi#48

# Fig. 3c-d Nsi#40 410C 2min

in-situ 350C 1min

	T(K)	[Tdiff]	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	2.5	0.1	1.08	20.24	2855.5	0.35
blue	2.5	0.1	1.08	20.24	2856.14	0.35
green	4.5	0.26	1.13	19.7	2813.95	0.355
green	4.6	0.25	1.13	19.69	2812.57	0.356
red	9.3	0.68	1.18	19.15	2771.82	0.361
red	8.9	0.6	1.17	19.18	2773.65	0.361
cyan	11.8	0.92	1.19	18.98	2759.36	0.362
cyan	11.2	0.79	1.19	19.02	2762.26	0.362

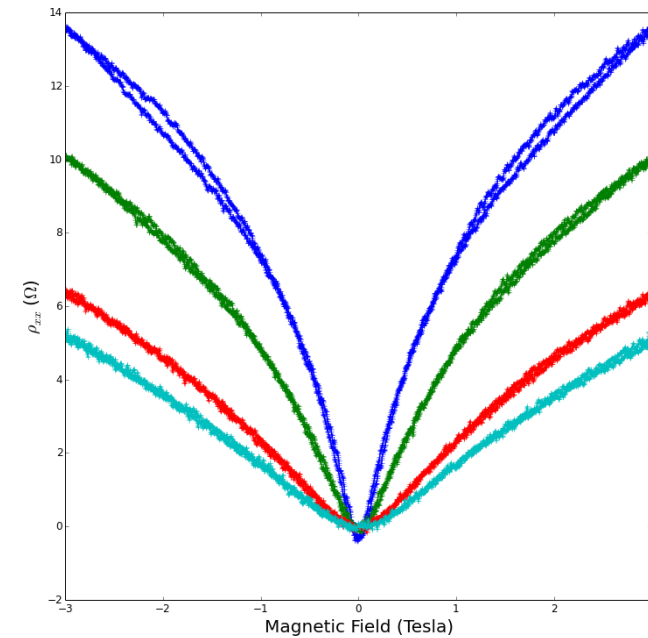


Sample nSi#40

# Fig. 3c-d Nsi#40 850C 2min

in-situ 350C 1min

	T(K)	T <sub>diff</sub>	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	2.4	0.2	1.3	57.95	829.07	1.206
blue	2.4	0.2	1.31	57.6	829.08	1.206
green	4.6	0.23	1.32	57.07	827.49	1.208
green	4.6	0.22	1.32	57.01	827.48	1.208
red	9	0.57	1.34	56.49	827.53	1.208
red	8.9	0.42	1.34	56.41	827.48	1.208
cyan	11.5	0.88	1.34	56.37	828.11	1.208
cyan	11	0.41	1.34	56.21	828.02	1.208

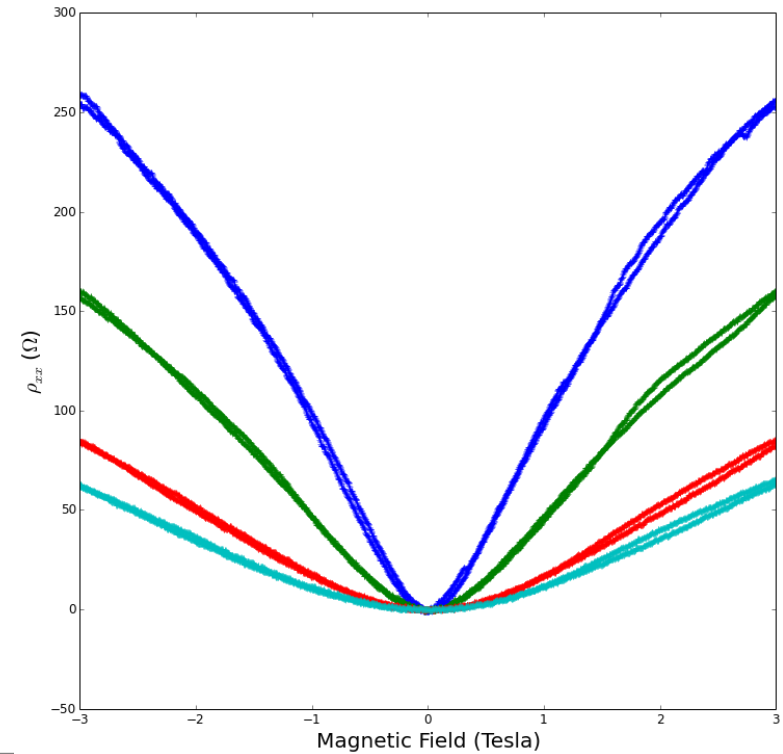


Sample nSi#40

1.5min 350C + 0.5min 405C

# Fig. 3c-d Nsi#129 410C 2min ex-situ

	T(K)	[Tdiff]	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	2.4	0.1	0.9	15.08	4602.88	0.217
blue	2.4	0.13	0.9	15.09	4599.48	0.217
green	4.5	0.12	0.97	14.3	4522.29	0.221
green	4.6	0.2	0.96	14.32	4520.52	0.221
red	8.8	0.25	1.03	13.68	4442.44	0.225
red	8.8	0.32	1.03	13.7	4442.55	0.225
cyan	11.3	0.4	1.05	13.47	4415.12	0.226



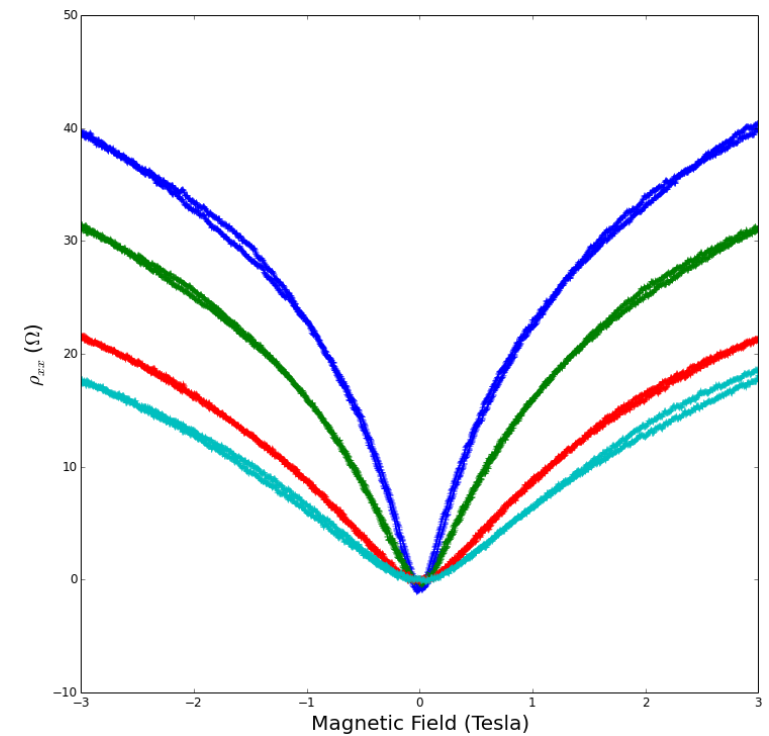
Sample nSi#129



# Fig. 3c-d Nsi#40 650C 2min

in-situ 350C 1min

	T(K)	[Tdiff]	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	2.3	0.1	1.18	34.89	1510.31	0.662
blue	2.4	0.1	1.18	34.89	1510.25	0.662
green	4.5	0.12	1.21	34.3	1499.08	0.667
green	4.5	0.16	1.21	34.3	1499.03	0.667
red	8.9	0.26	1.24	33.69	1489.42	0.671
red	8.9	0.26	1.24	33.7	1489.41	0.671
cyan	11.5	0.58	1.25	33.47	1486.61	0.673
cyan	11.1	0.61	1.25	33.51	1486.89	0.673

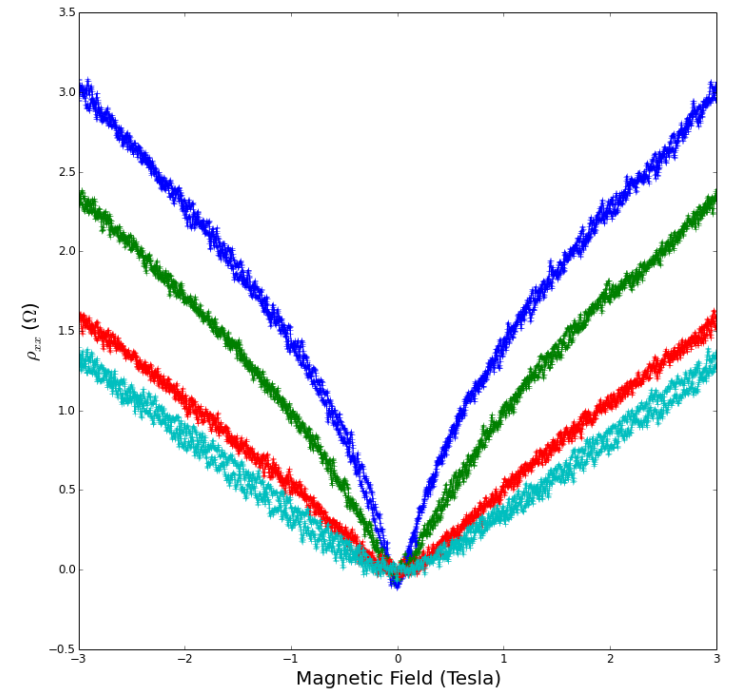


Sample nSi#40

1.5min 350C + 0.5min 405C

# Fig. 3c-d Nsi#129 850C 2min

	T(K)	[Tdiff]	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	2.3	0.06	3.23	55.61	347.79	2.875
blue	2.3	0.06	3.24	55.46	347.78	2.875
green	4.4	0.05	3.25	55.28	347.42	2.878
green	4.5	0.29	3.3	54.38	347.4	2.879
red	8.8	0.23	3.31	54.31	347.27	2.88
red	8.7	0.28	3.26	55.13	347.25	2.88
cyan	11.3	0.98	3.3	54.36	347.41	2.878
cyan	10.8	0.51	3.27	55.02	347.34	2.879

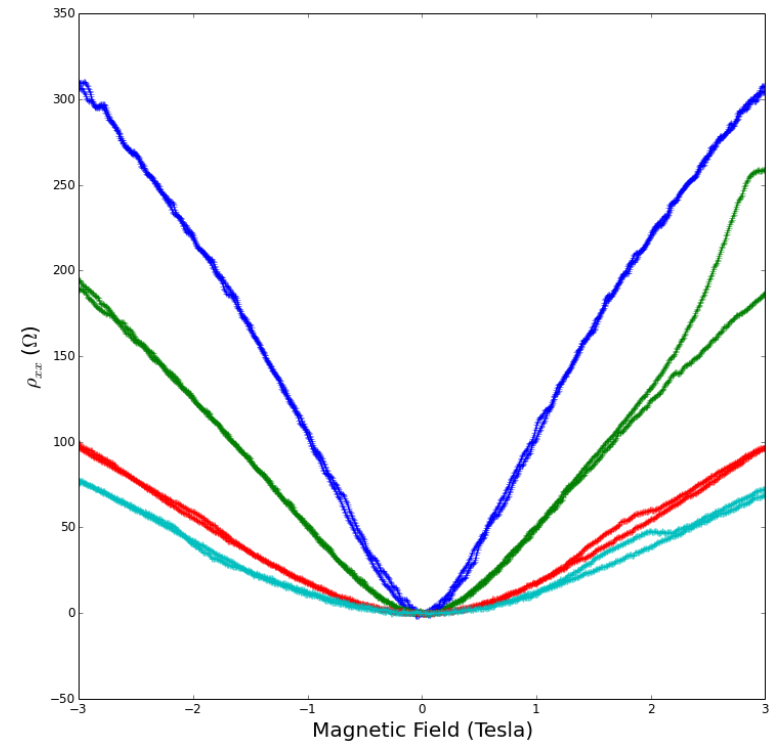


Sample nSi#129

1.5min 350C + 0.5min 405C

# Fig. 3c-d Nsi#129 in-situ

	T(K)	[Tdiff]	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	2.5	0.06	0.85	13.42	5500.54	0.182
blue	2.5	0.09	0.84	13.43	5502.46	0.182
green	4.4	0.89	0.9	12.88	5388.98	0.186
green	4.5	0.1	0.91	12.78	5387.05	0.186
red	8.9	0.23	0.98	12.13	5270.01	0.19

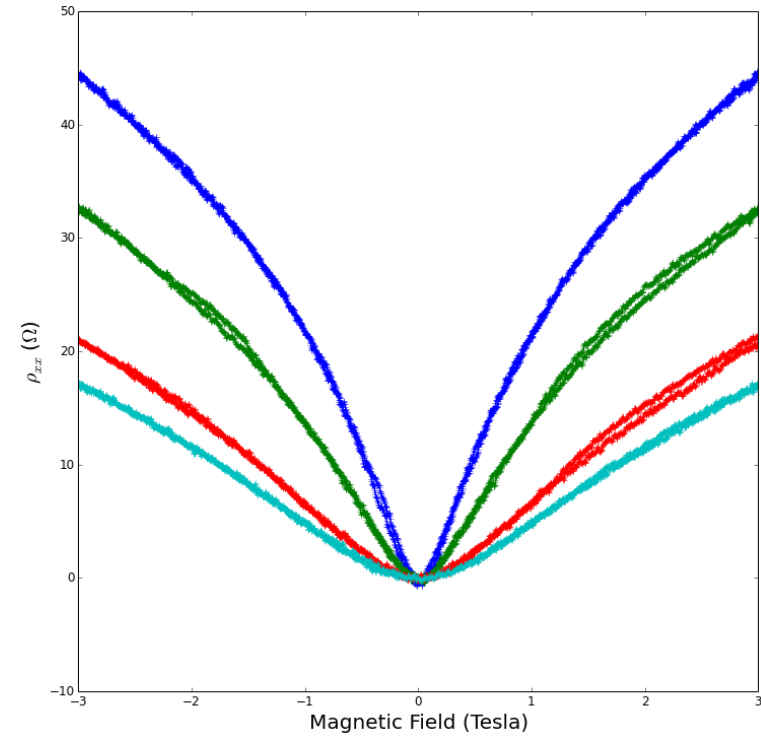


Sample nSi#129

1.5min 350C + 0.5min 405C

# Fig. 3c-d Nsi#129 650C 2min

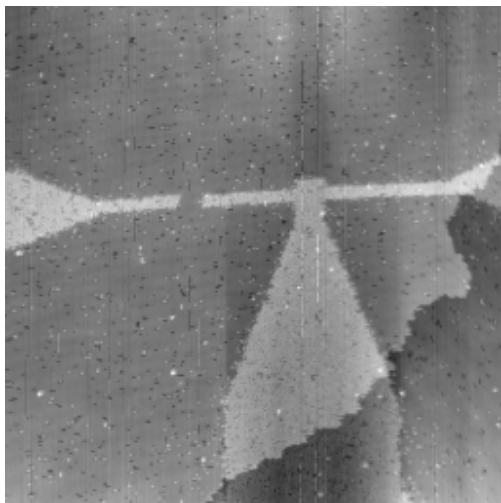
	T(K)	[Tdiff]	Ns(nm <sup>-2</sup> )	Mu(cm <sup>2</sup> /Vs)	Rho0(Ohm)	Sig0(mS)
blue	2.4	0.08	1.11	33.05	1703.84	0.587
blue	2.3	0.06	1.11	33.03	1704.06	0.587
green	4.5	0.17	1.14	32.34	1692.09	0.591
green	4.5	0.22	1.14	32.35	1691.79	0.591
red	8.9	0.31	1.17	31.69	1682.47	0.594
red	8.7	0.42	1.17	31.71	1682.7	0.594



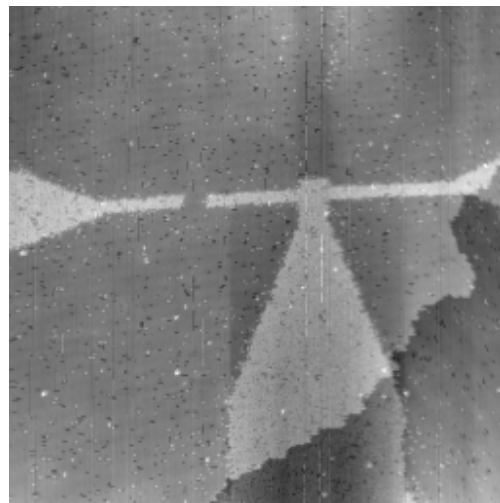
Sample nSi#129

# Fig. 4

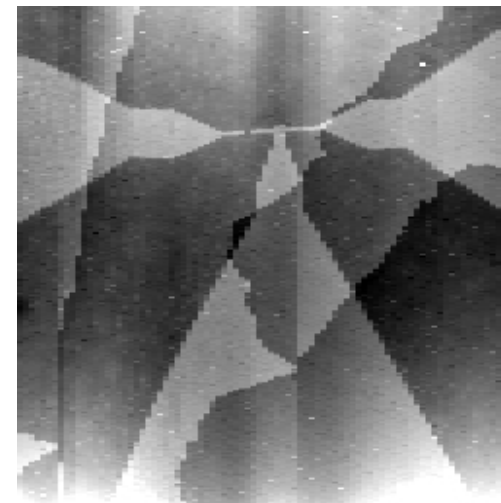
raw STM images  
of device



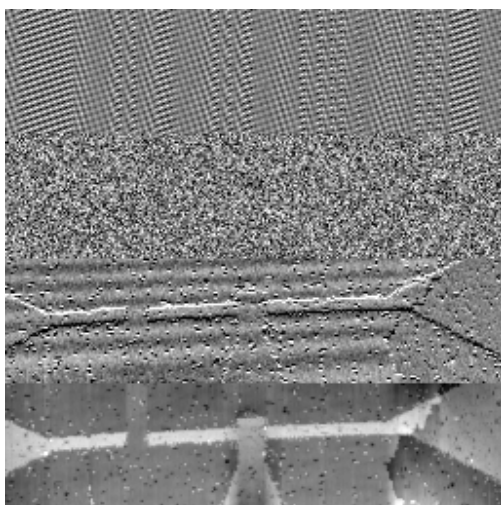
A160620.144723.dat



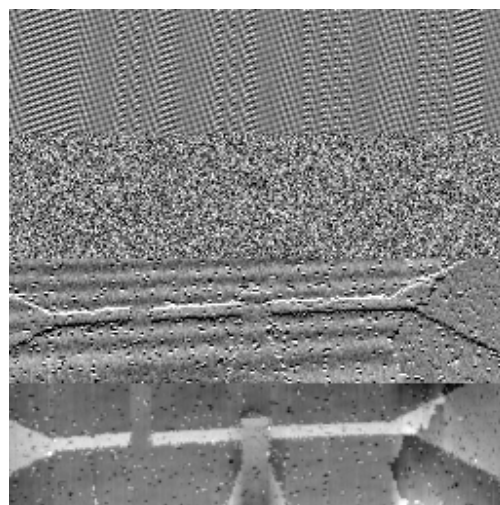
A160620.144723.X.dat



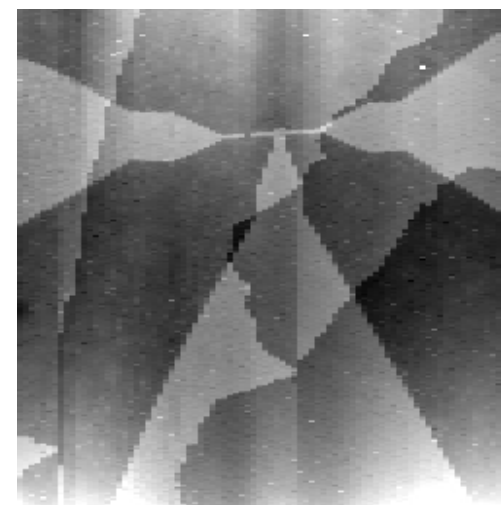
A160620.145933.dat



A160620.102742.dat



A160620.102742.X.dat

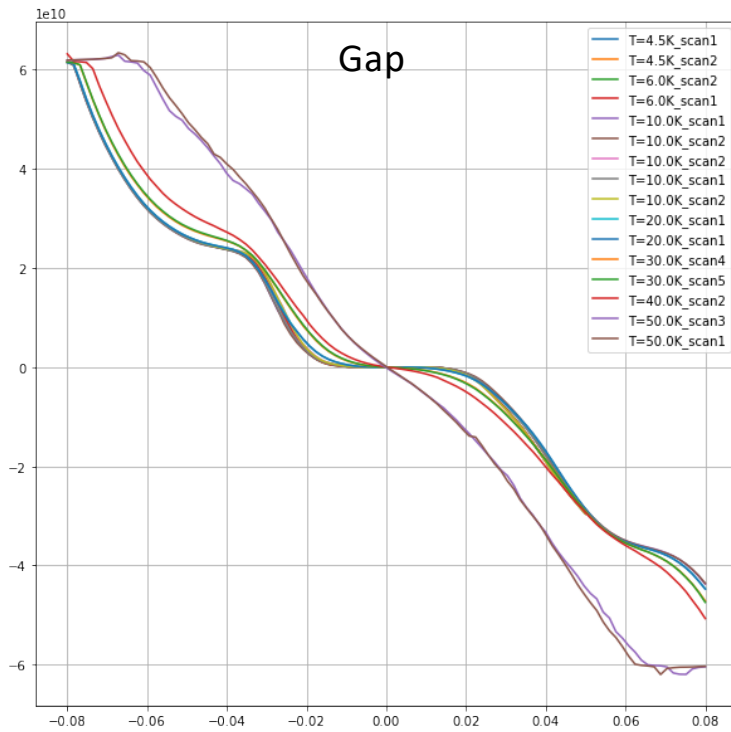


A160620.145933.X.dat

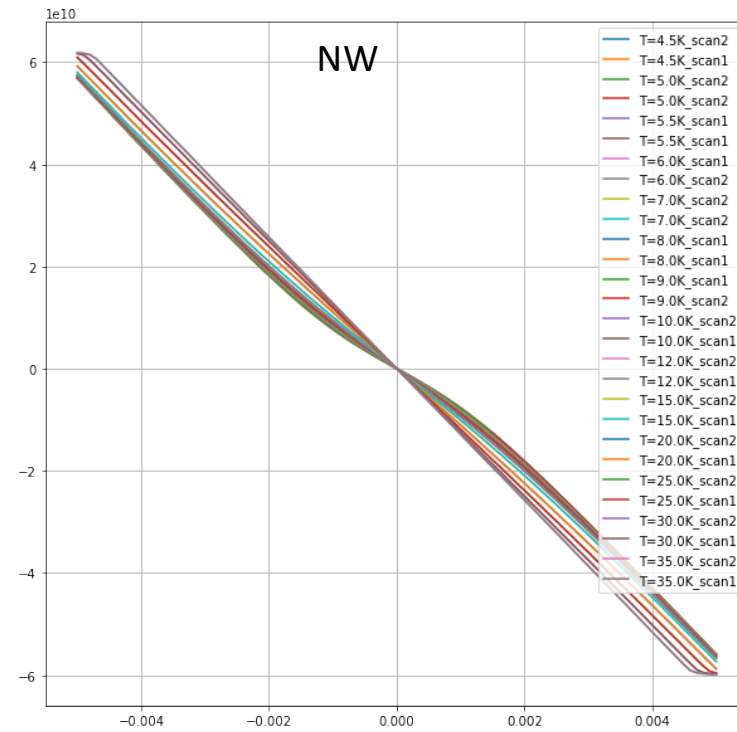
# Fig. 4

at  $T > 40\text{K}$  substrate leakage  
dominates conductance

full dataset



slight non-linearity due to  
Schottky contacts in this device



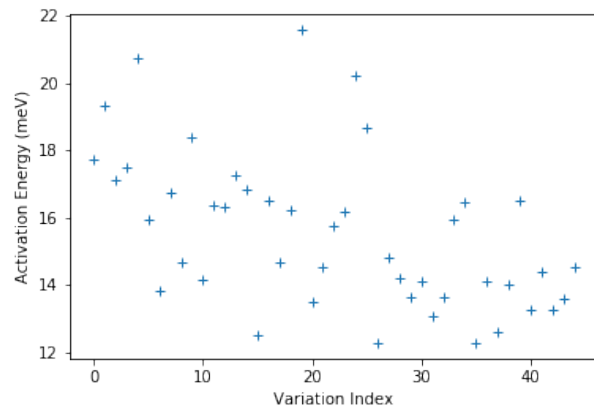
D12\_IV\_NWGap(21-16)\_04.5K001.dat D12\_IV\_NWGap(21-16)\_10.0K005.dat D12\_IV\_NWGap(21-16)\_04.5K002.dat D12\_IV\_NWGap(21-16)\_20.0K001.dat  
D12\_IV\_NWGap(21-16)\_06.0K001.dat D12\_IV\_NWGap(21-16)\_20.0K002.dat D12\_IV\_NWGap(21-16)\_06.0K002.dat D12\_IV\_NWGap(21-16)\_30.0K001.dat  
D12\_IV\_NWGap(21-16)\_10.0K001.dat D12\_IV\_NWGap(21-16)\_30.0K002.dat D12\_IV\_NWGap(21-16)\_10.0K002.dat D12\_IV\_NWGap(21-16)\_40.0K001.dat  
D12\_IV\_NWGap(21-16)\_10.0K003.dat D12\_IV\_NWGap(21-16)\_50.0K001.dat D12\_IV\_NWGap(21-16)\_10.0K004.dat D12\_IV\_NWGap(21-16)\_50.0K002.dat

## Fig. 4 Determination of the activation energy for the gap section of the device

Fit Procedure for activation energy:

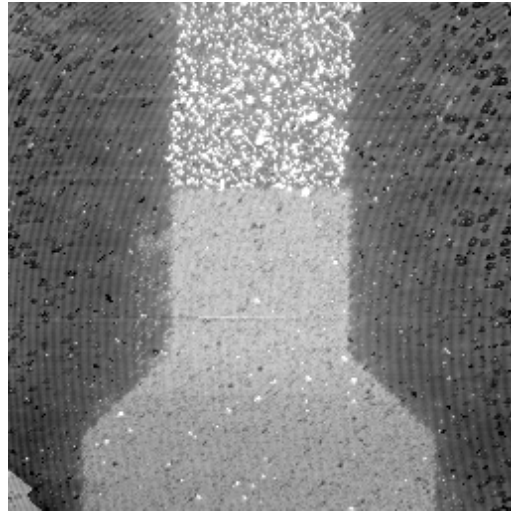
- fit polygon (polygon order  $n = 14$  to  $23$ ) to region around  $|V_{\text{bias}}| < c_0 = 30, 32, 34, 36, 38, 40$  mV
- analytically take derivative of polygon
- average conductance over region  $|V_{\text{bias}}| < 5$  mV
- fit average conductance values as a function of temperature
- vary  $n$  and  $c_0$  in the range specified above to check robustness of fit

The plot below shows the activation energy for the different parameter variations and yields the uncertainty of  $\pm 5$  meV stated in the paper for the activation energy.

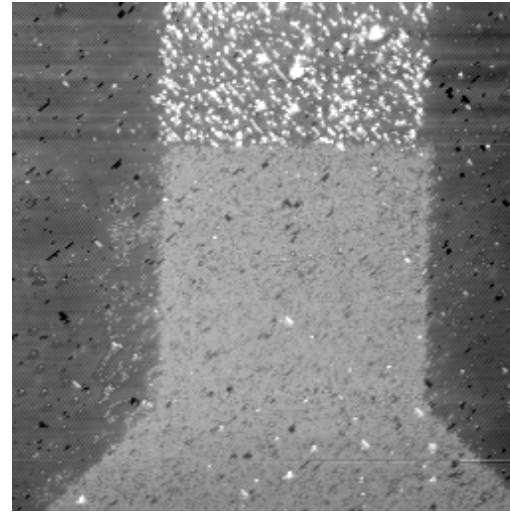


# Fig. 5

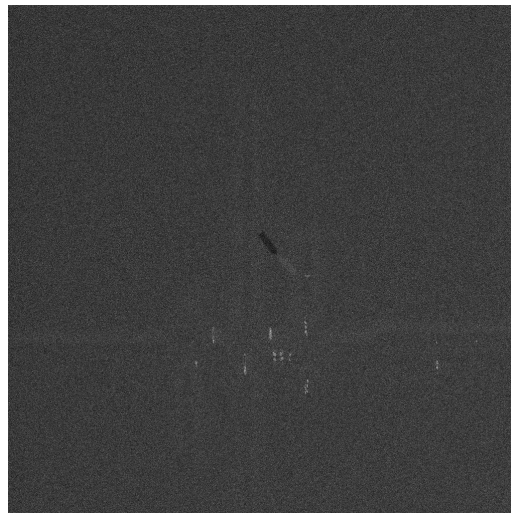
raw SEM and STM  
images of device



A160330.144902.dat



A160330.143938.dat



sem\_pn\_device\_overv.pdf

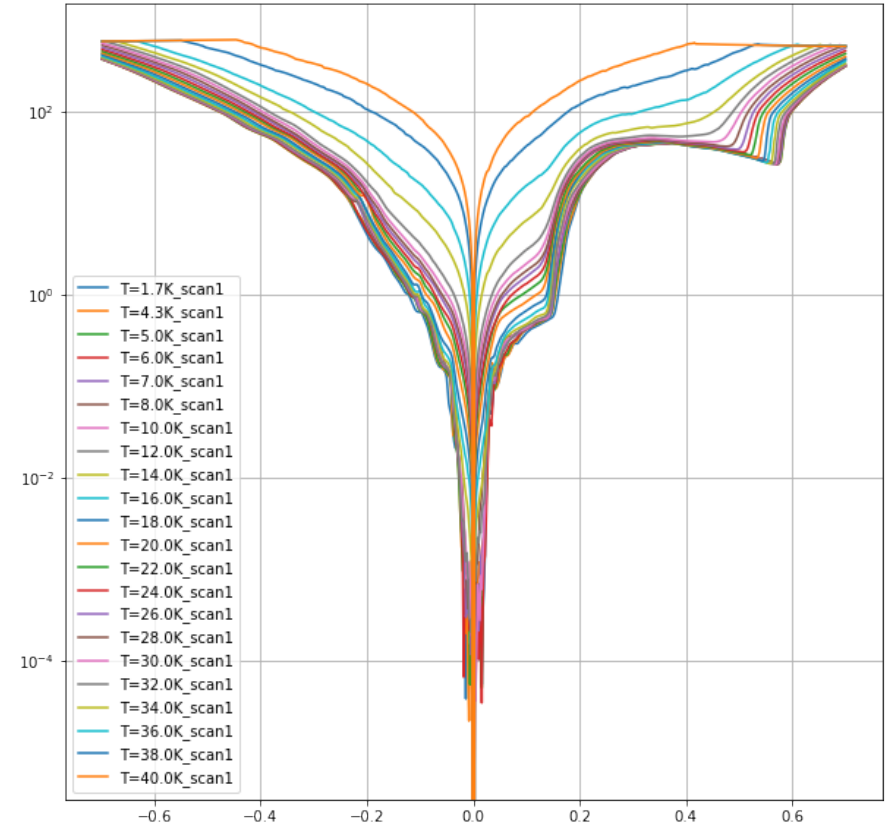
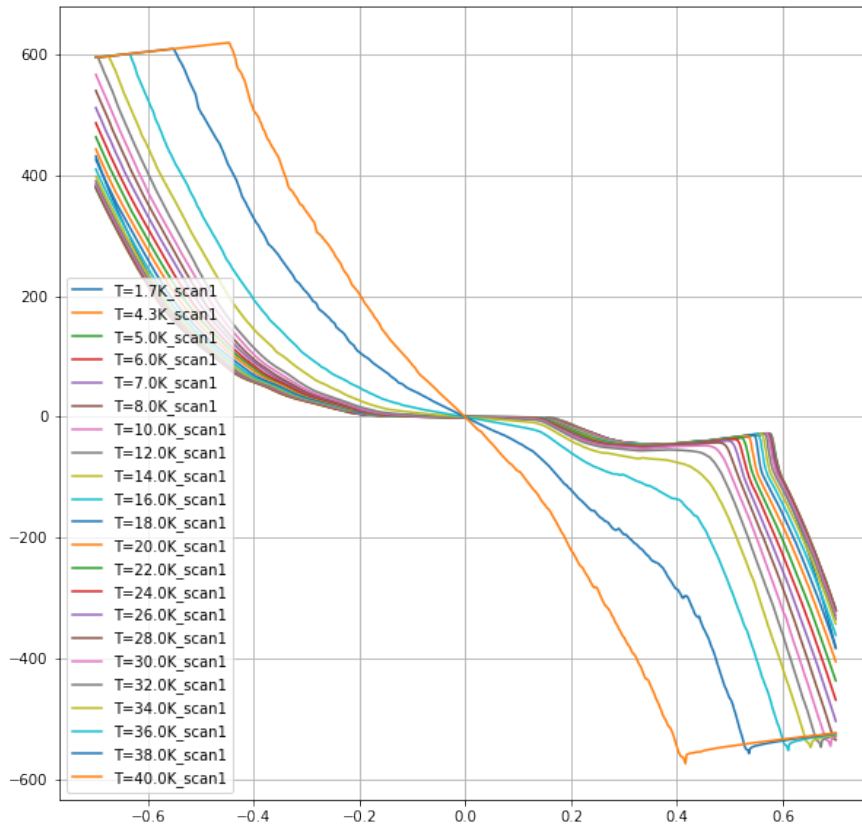


sem\_pn\_device\_zoom.pdf



# Fig. 5

full dataset



D02\_IV\_curve\_10M\_03-04\_01.7K001.dat D02\_IV\_curve\_10M\_03-04\_20.0K001.dat D02\_IV\_curve\_10M\_03-04\_04.3K001.dat D02\_IV\_curve\_10M\_03-04\_22.0K001.dat  
D02\_IV\_curve\_10M\_03-04\_05.0K001.dat D02\_IV\_curve\_10M\_03-04\_24.0K001.dat D02\_IV\_curve\_10M\_03-04\_06.0K001.dat D02\_IV\_curve\_10M\_03-04\_26.0K001.dat  
D02\_IV\_curve\_10M\_03-04\_07.0K001.dat D02\_IV\_curve\_10M\_03-04\_28.0K001.dat D02\_IV\_curve\_10M\_03-04\_08.0K001.dat D02\_IV\_curve\_10M\_03-04\_30.0K001.dat  
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